Fig. 1

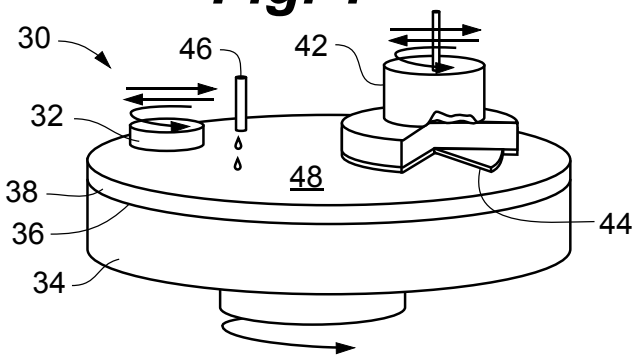


Fig. 2

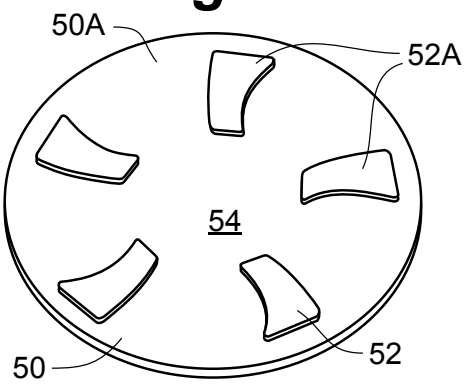


Fig. 3

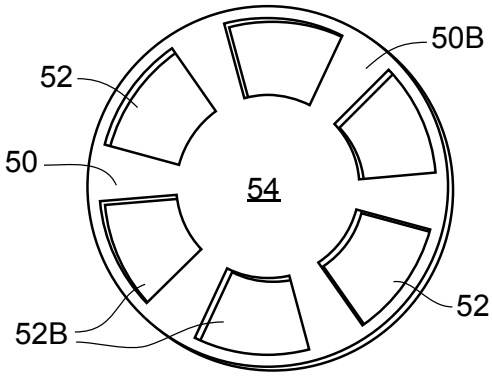


Fig. 4

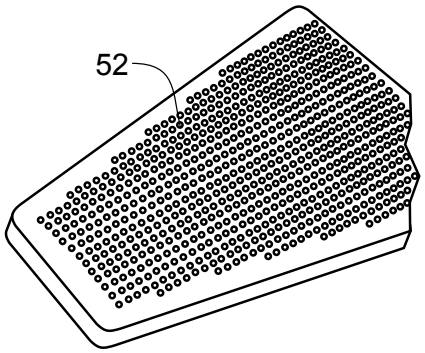


Fig. 5

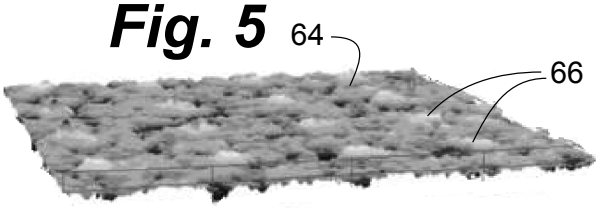


Fig. 6a

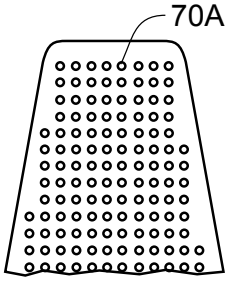


Fig. 6b

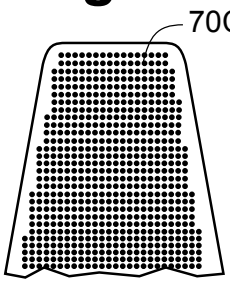


Fig. 7

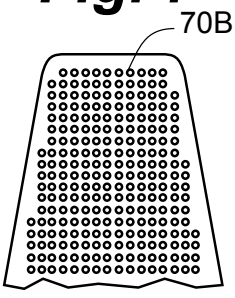


Fig. 8

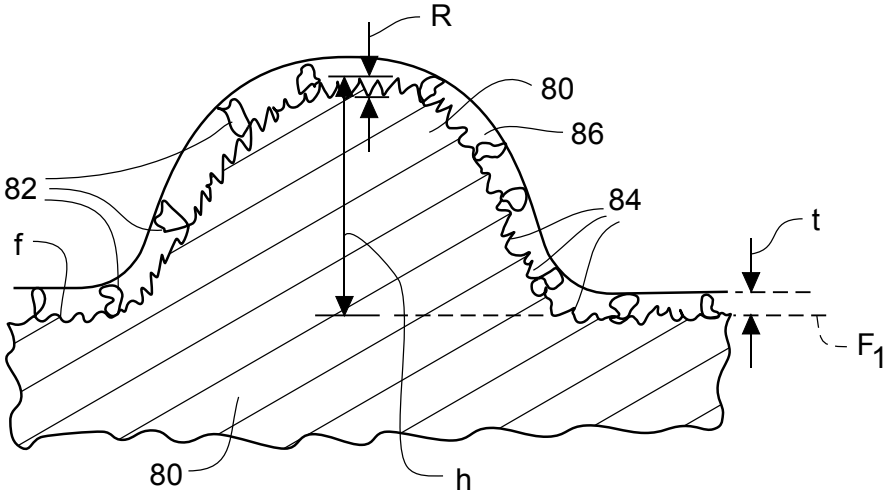


Fig. 14

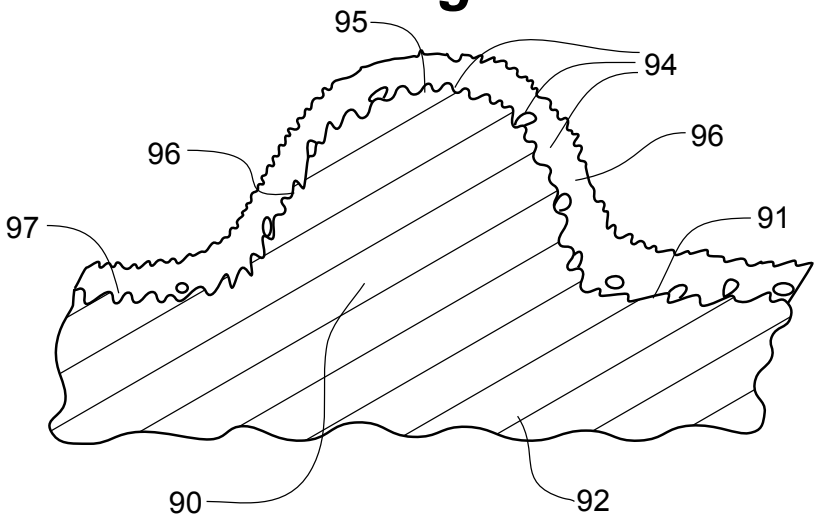


Fig. 15

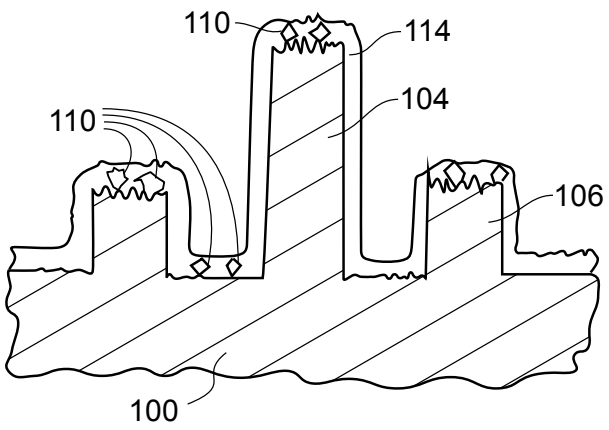
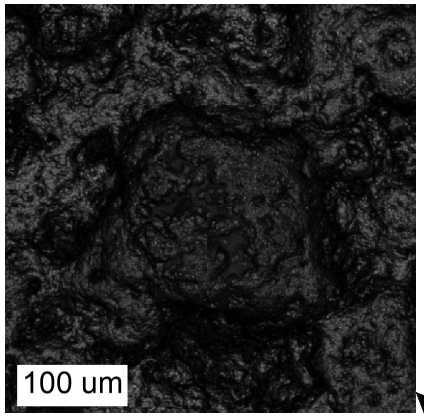
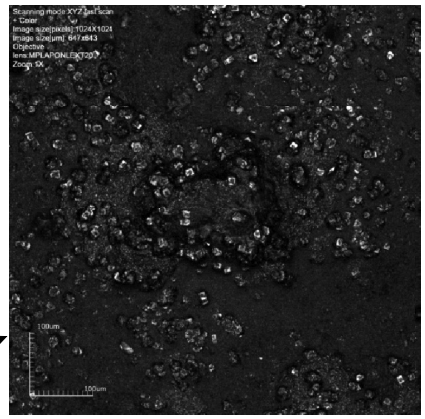


Fig. 10



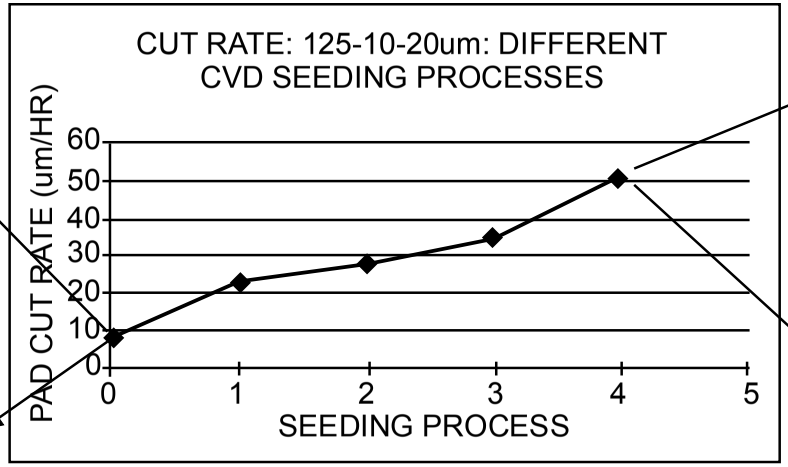
FEATURE ON SiC SURFACE

Fig. 12



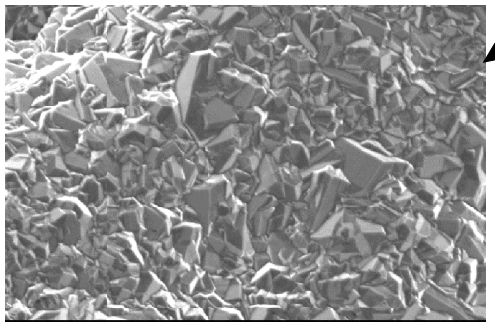
FEATURE ON SiC SURFACE

Fig. 9



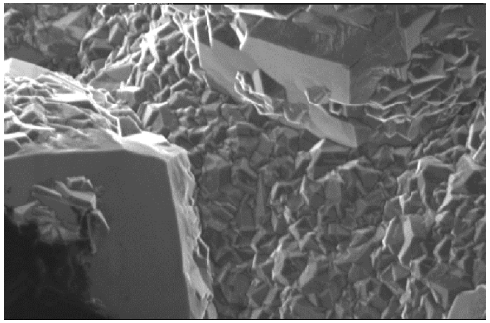
SEEDING PROCESS 1; 1-2 um
SEEDING PROCESS 2; 2-4 um
SEEDING PROCESS 3; 4-8 um
SEEDING PROCESS 4; 6-12 um

Fig. 11



SEM OF CVD SURFACE

Fig. 13



SEM OF CVD SURFACE